

Integrated Dimensional and Electrical Metrology of Nanostructures

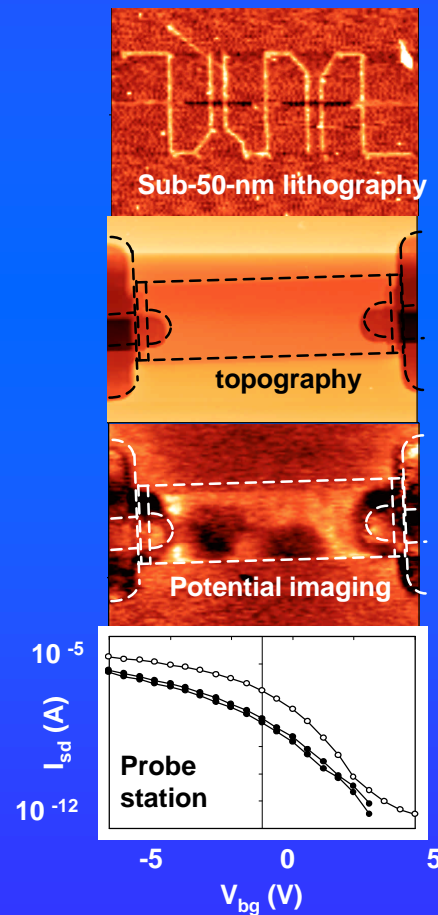
Project Leader: John Dagata

2001 Deliverables

- Develop the instrumentation and techniques necessary to integrate simultaneous dimensional and electrical measurements using local-probe techniques
- Present a paper at the SPIE Microlithography meeting on the methodology

Customers and Collaborators

- University of North Carolina, Chapel Hill
- Electrotechnical Laboratory (ETL), Japan,
- Universitat Autònoma de Barcelona, Spain
- Matsushita Electrical, Japan.



FY 2000 Accomplishments

- Constructed integrated probe station and scanned probe microscope
- Designed and fabricated test device: silicon-on-insulator field-effect transistor
- Initial test results illustrated at left